

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the PATENT application of:

Applicant: Benveniste et al.

Application No.: 10/600,775

Filing Date: June 20, 2003

Title: THIN MAGNETRON STRUCTURES FOR PLASMA GENERATION
IN ION IMPLANTATION SYSTEMS

PRELIMINARY AMENDMENT

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please amend the above-identified application as indicated below.

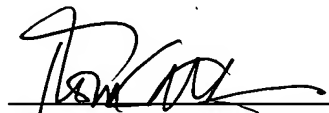
In the Specification:

Page 1, after the title, insert the following paragraph:

--Related Application

This application claims priority to U.S. Application No. 60/470,926 filed May 15, 2003, which is entitled "High Mass Resolution Magnet for Ribbon Beam Ion Implanters".

Respectfully submitted,
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CERTIFICATE OF MAILING

I hereby certify that this paper (along with any paper or item referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first-class mail in an envelope addressed to Mail Stop Non-Fee Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Date: July 14, 2003

Christine Gillroy
Christine Gillroy

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